

Production of Quasi-Monochromatic GeV Photons by Compton Scattering using Undulator X-ray Radiation at SPring-8

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Outline

- Motivation
- LEPS2 Activity at SPring-8
- Theory of Backward Compton Scattering of Quasi-Monochromatic γ -ray
- Preliminary Reflectivity Measurements of Single Crystal
- Plan of Test Experiment for γ -ray Production
- Summary

Motivation

- BCS using laser (infrared to ultra-violet) established with successful results, but extension of the maximum photon energy of γ -ray opens new fields of the photo production experiments of nuclear and particle physics



LEP and LEP2(BL31LEP) at SPring-8

- Quasi-monochromatic γ -ray



No tagging system (γ -ray intensity and energy are measured)

- In SR facility, many high power X-ray undulators. Very attractive to use as incident photon source for BCS



Photon energy close to the kinematic limit

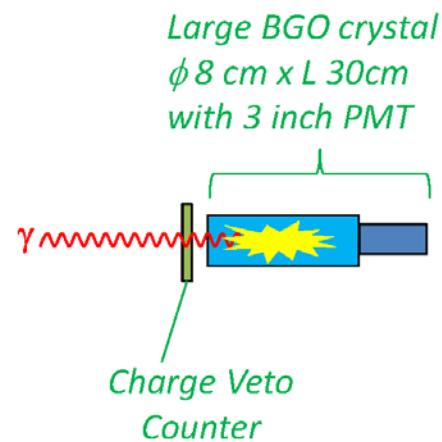
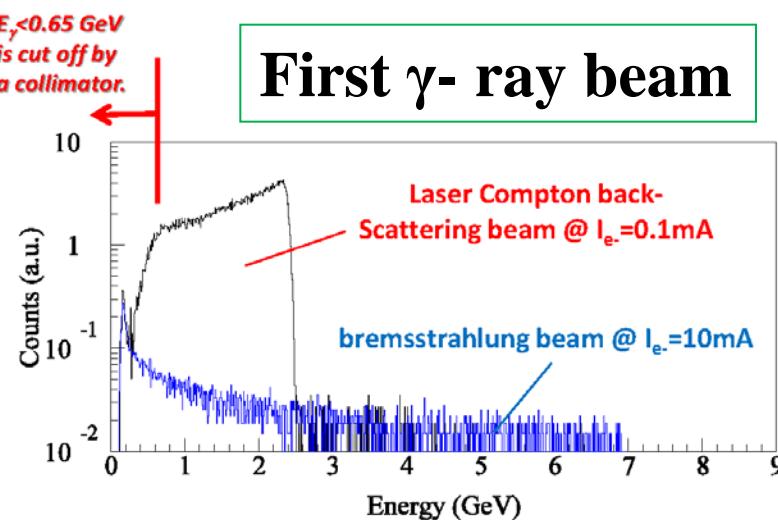
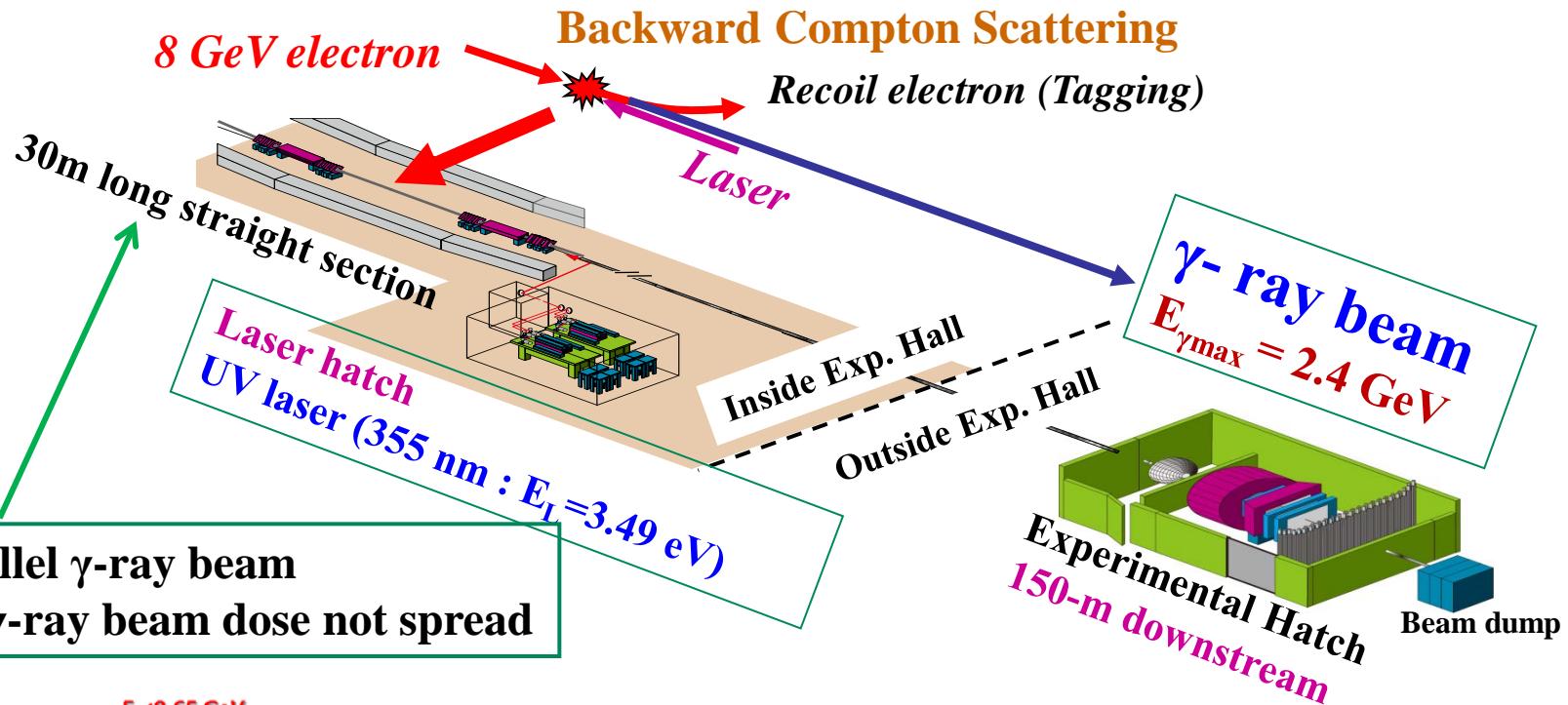
- Single crystal with high-reflectivity at normal-incidence (K-J. Kim et al.)



X-ray photon reflected back by a single crystal

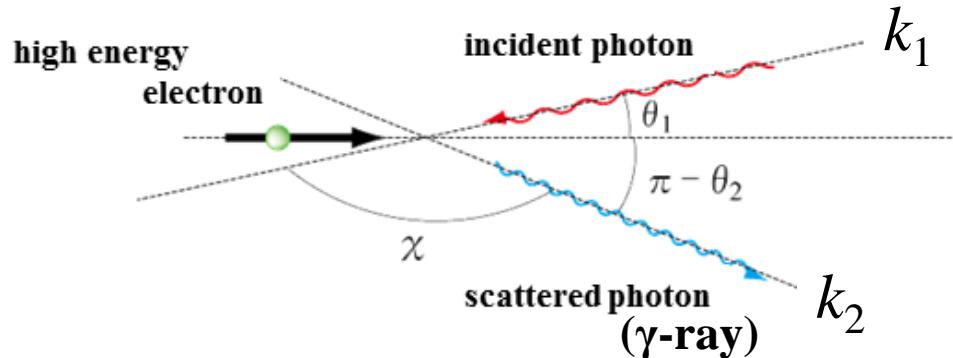
- Low energy operation in future SPring-8

BL31LEP constructed at long straight section of SPring-8



Theory of Backward Compton Scattering

Schematic diagram of BCS



$$k_2 = k_1 \frac{1 + \beta \cos \theta_1}{1 + \beta \cos \theta_2 + \frac{k_1}{E_e} (1 - \cos \chi)} \quad (1)$$

In case of head-on collision, maximum energy of scattered Photon :

$$k_{2\max} = \frac{k_1(1 + \beta)}{1 + \beta + \frac{2k_1}{E_e}} \approx \frac{4k_1 E_e^2}{(m_e c^2)^2 + 4k_1 E_e} \quad (2)$$

When k_1 is 10 keV, E_e = 8 GeV $\rightarrow k_{2\max} \sim 8$ GeV

(photon energy of γ -ray is almost equal to electron energy).

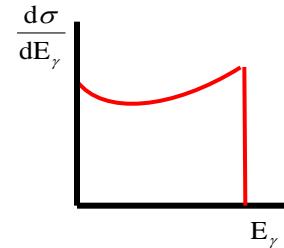
Spectrum shape (Milburn, 1963)

$$\frac{1}{\sigma_0} \frac{d\sigma}{d(k_2/E_e)} = \frac{3}{16\lambda} \left[\frac{\lambda^2(1-x)^2}{1+\lambda(1-x)} + 2(1+x^2) + O[x^n] \right] \quad (3)$$

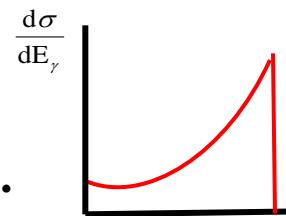
σ_0 : Thomson scattering cross-section,
 $\lambda = 2\gamma k_1/m_e c^2$, $x = \cos\theta_0$ (θ_0 : photon scattering angle)

For small k_1 (e. g. laser light, $E_1 = 3.49$ eV),
the second term of Eq. (3) is dominant.

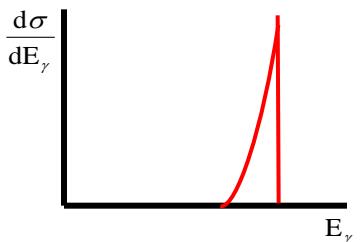
γ -ray spectrum is the parabolic shape
with wide photon energy range.

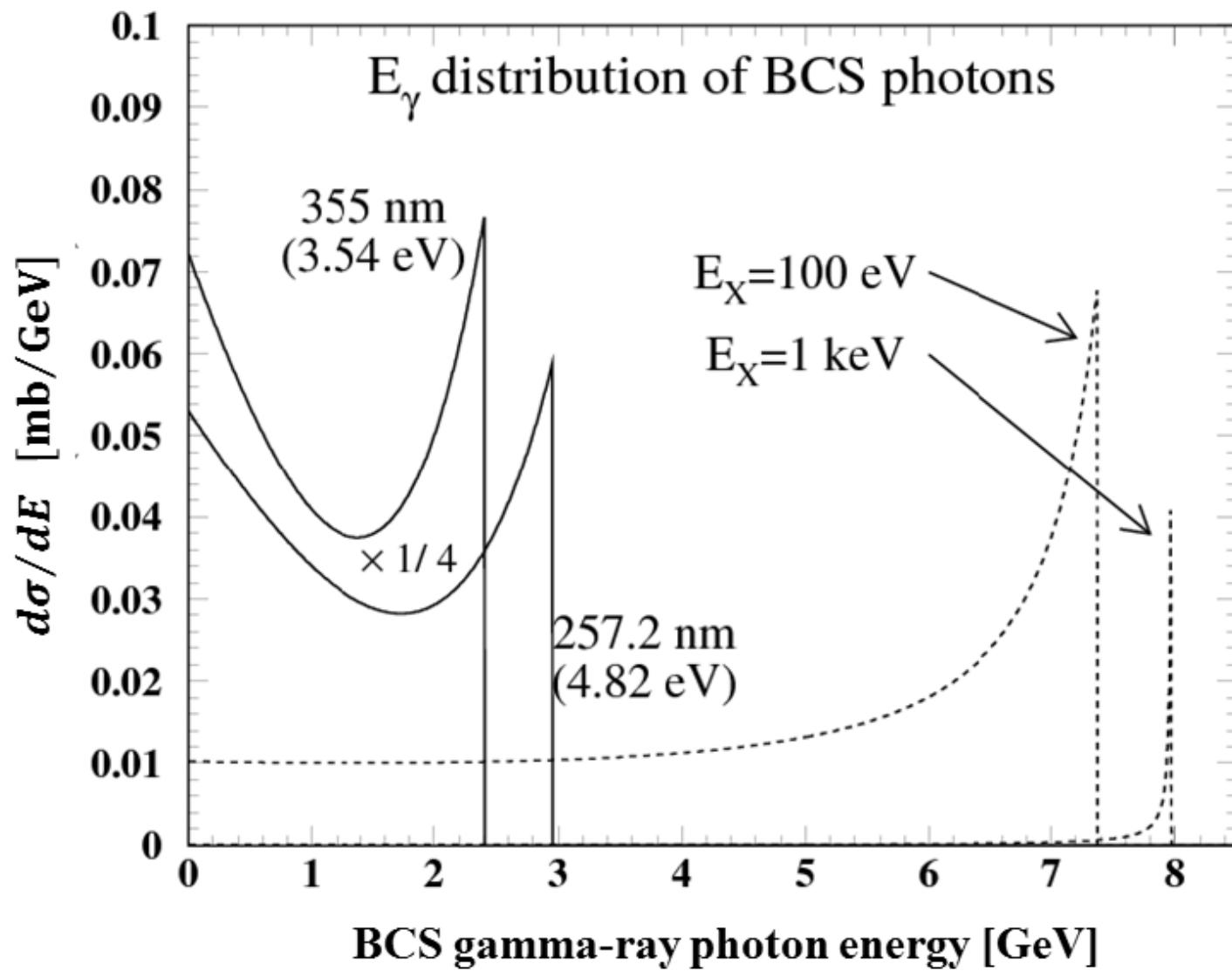


For large k_1 (e. g. undulator, $E_1 > 100$ eV),
the first term is dominant and
 γ -ray spectrum damps in the low energy region.

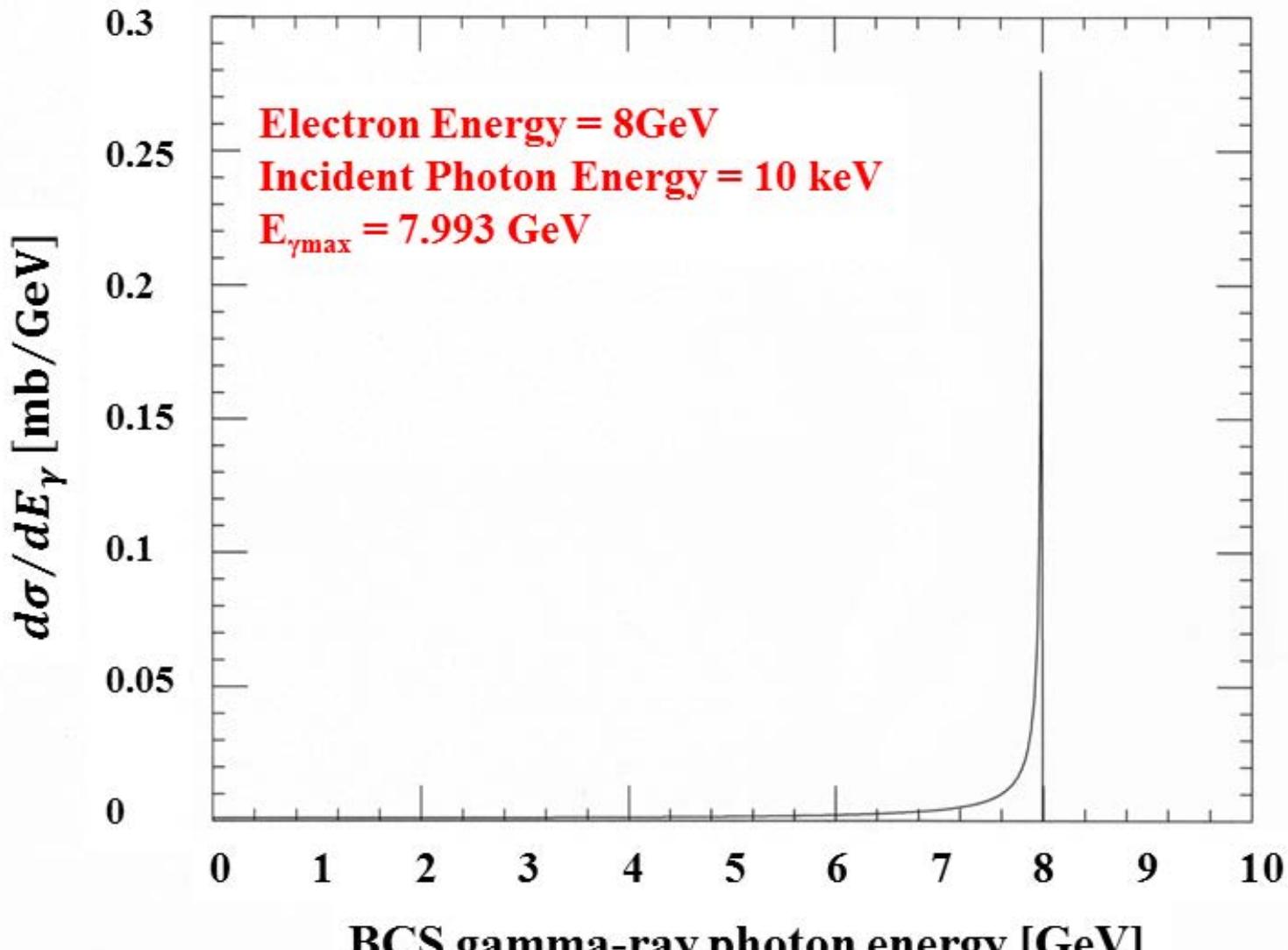


For very large k_1 (e. g. hard X-ray undulator, $E_1 > 5$ keV),
higher-order term x^n ($n > 2$) of Eq. (3) becomes important.
 γ -ray spectrum uprises steeply near the maximum BCS gamma-ray of $k_{2\max}$.



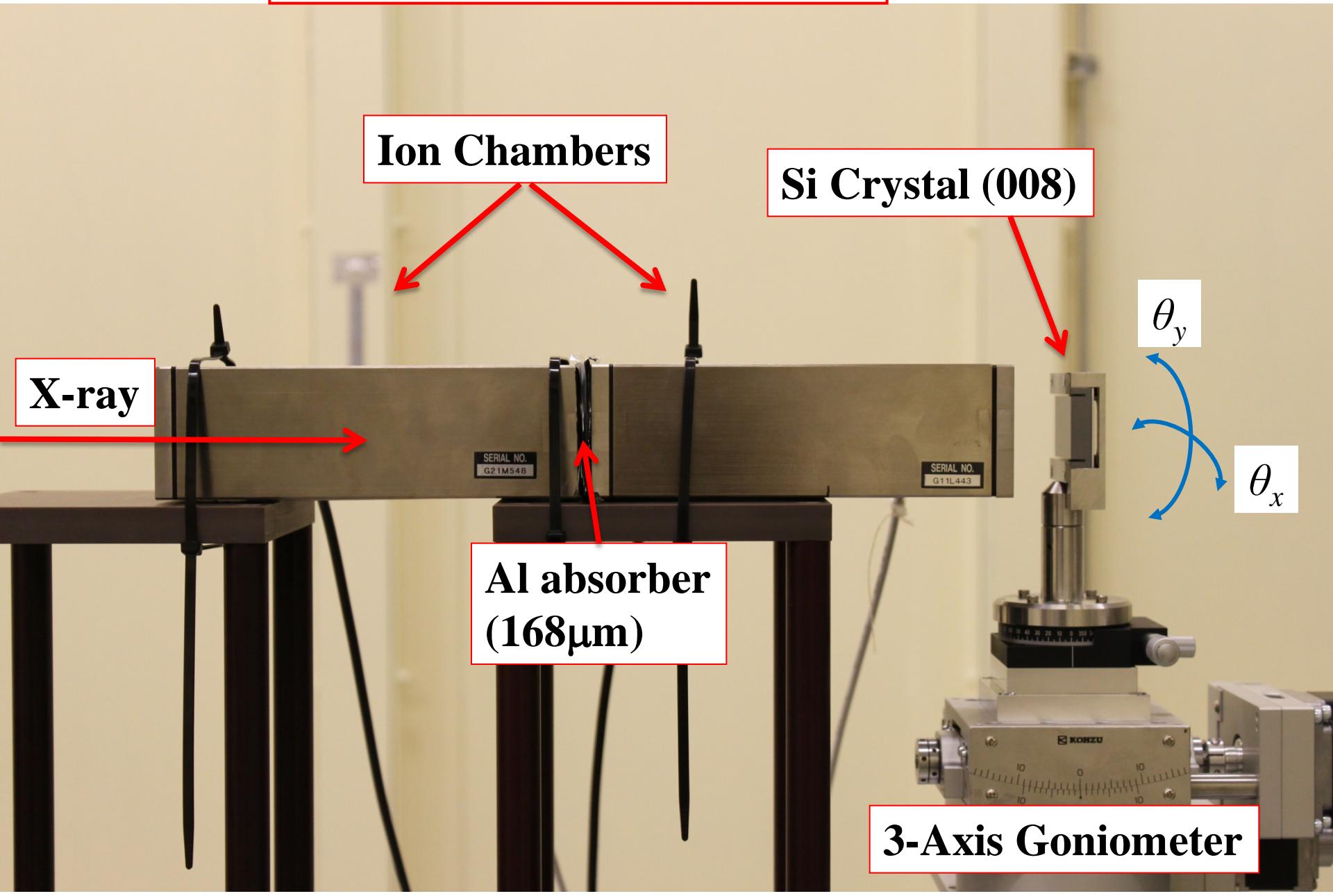


Calculated γ -ray distribution as a parameter of incident photon energy



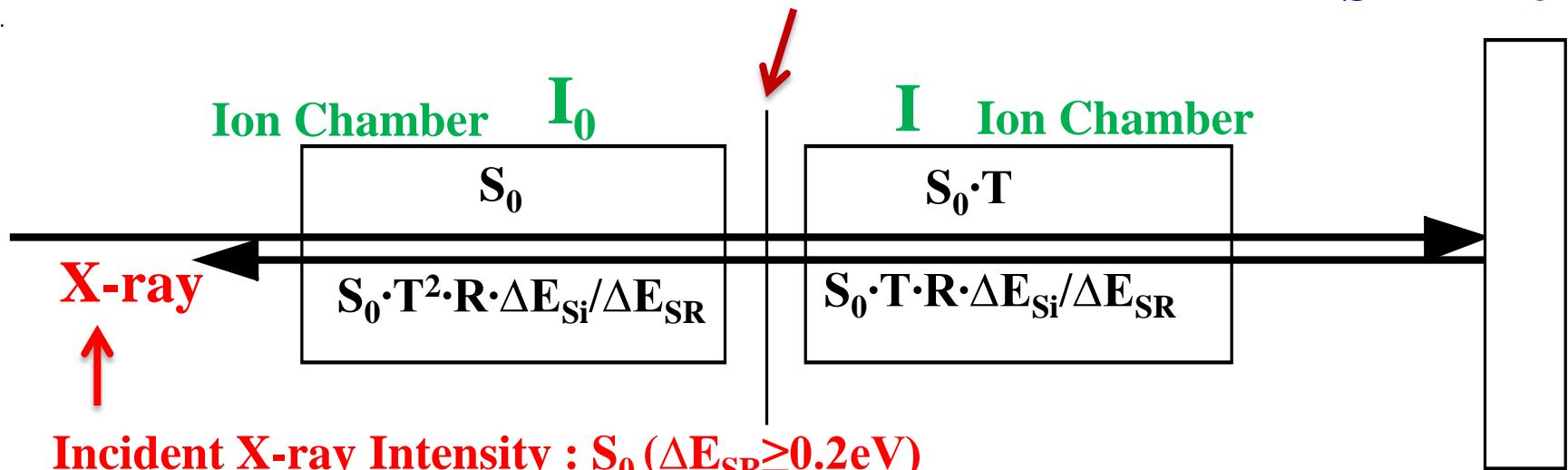
10keV incident X-ray and Produced γ -ray in kinematic limit

Reflectivity Measurement



Al absorber (Thickness = 168μm) : T~0.23

Si Mirror



$$\frac{I}{I_0} = C \cdot \frac{S_0 \cdot T + S_0 \cdot T \cdot R \cdot \frac{\Delta E_{Si}}{\Delta E_{SR}}}{S_0 + S_0 \cdot T^2 \cdot R \cdot \frac{\Delta E_{Si}}{\Delta E_{SR}}} = C \cdot T \left(1 + R \cdot \frac{\Delta E_{Si}}{\Delta E_{SR}} \right) = 0.23C(1 + 0.3R)$$

$R(\Delta E_{Si} \sim 60\text{meV})$

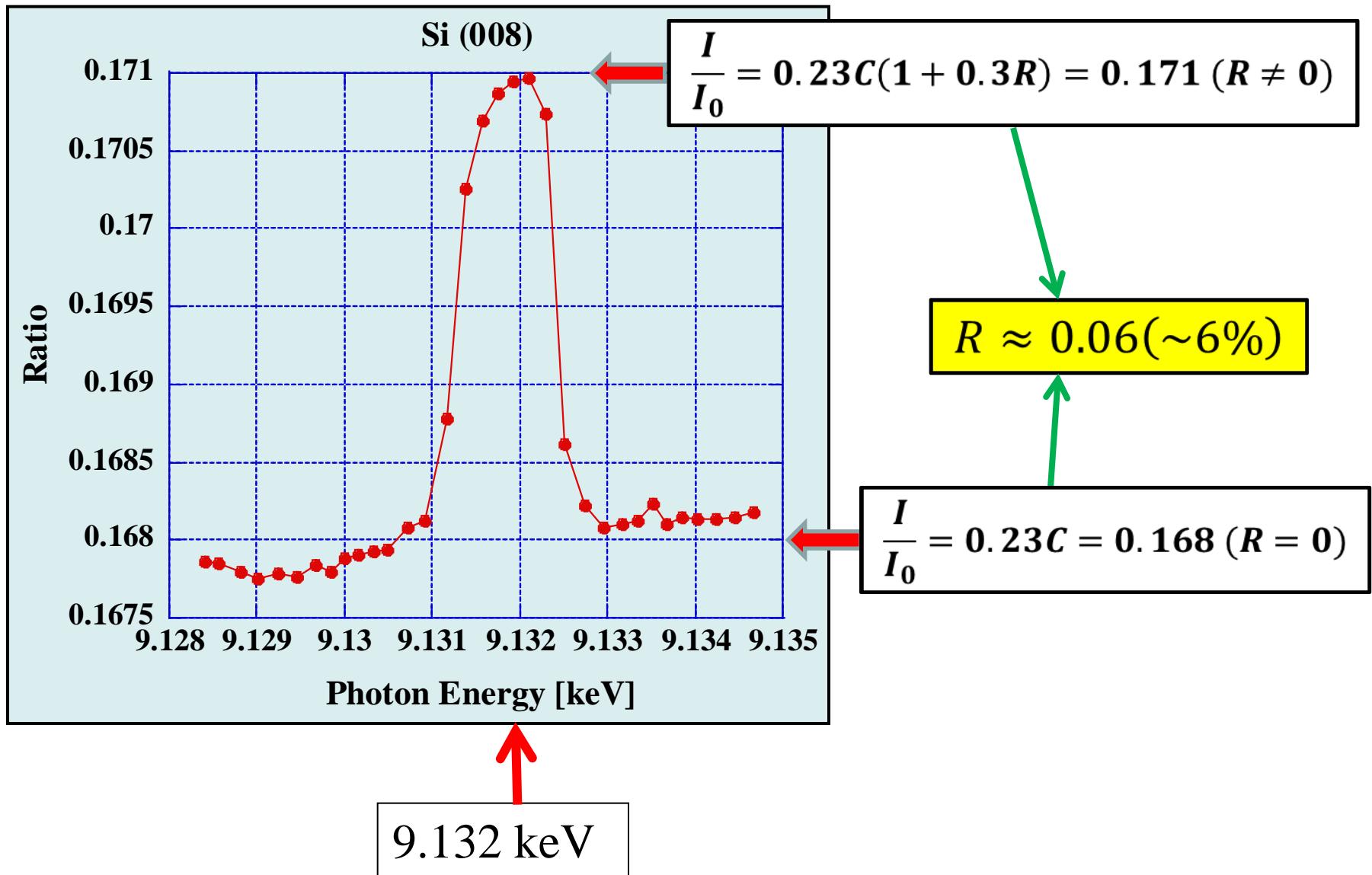
$$\frac{I}{I_0} = 0.23C = 0.168 \quad (R=0)$$

$$\frac{I}{I_0} = 0.23C(1 + 0.3R) = 0.171 \quad (R \neq 0)$$

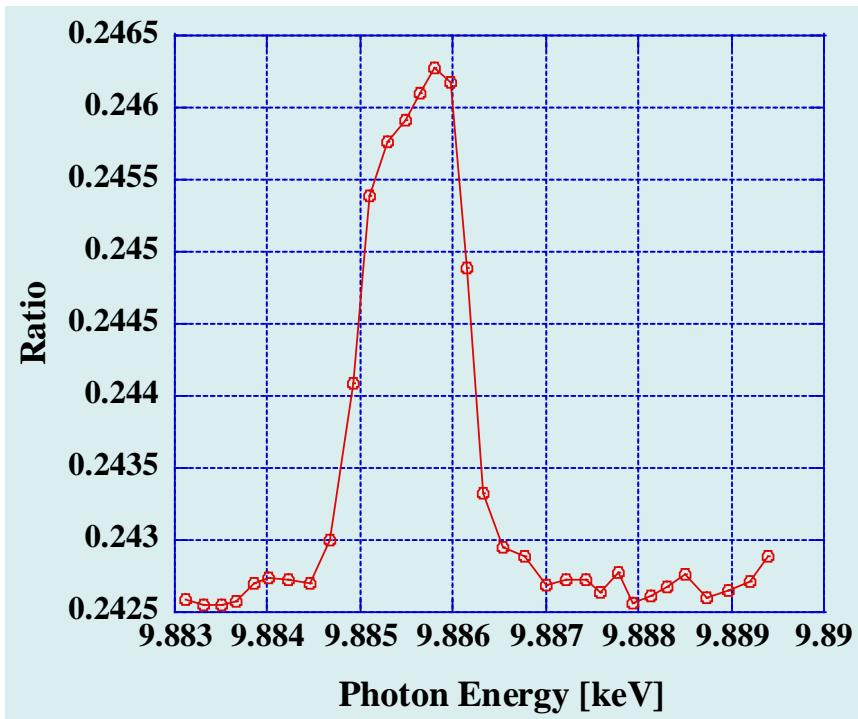
$R \approx 0.06 (\sim 6\%)$

cf. Si (333) $R \approx 0.11 (\sim 11\%)$, Si (555) $R \approx 0.05 (\sim 5\%)$

Si (008) Bragg Reflection at normal-incidence



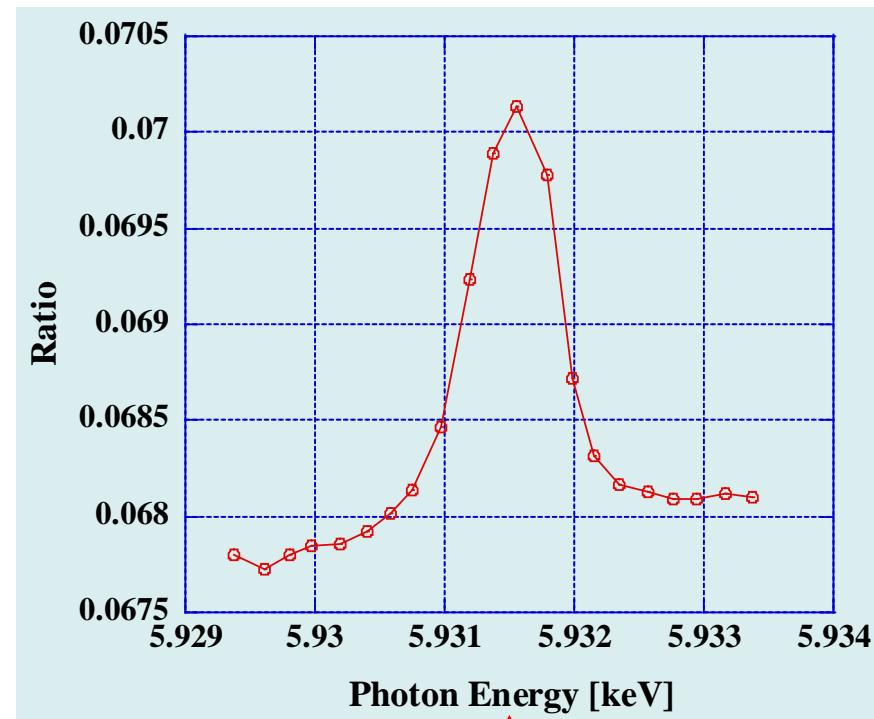
$\text{Si } (5\ 5\ 5)$



9.886 keV

$\text{Si } (555) \ R \approx 0.05 \ (\sim 5\%)$

$\text{Si } (3\ 3\ 3)$

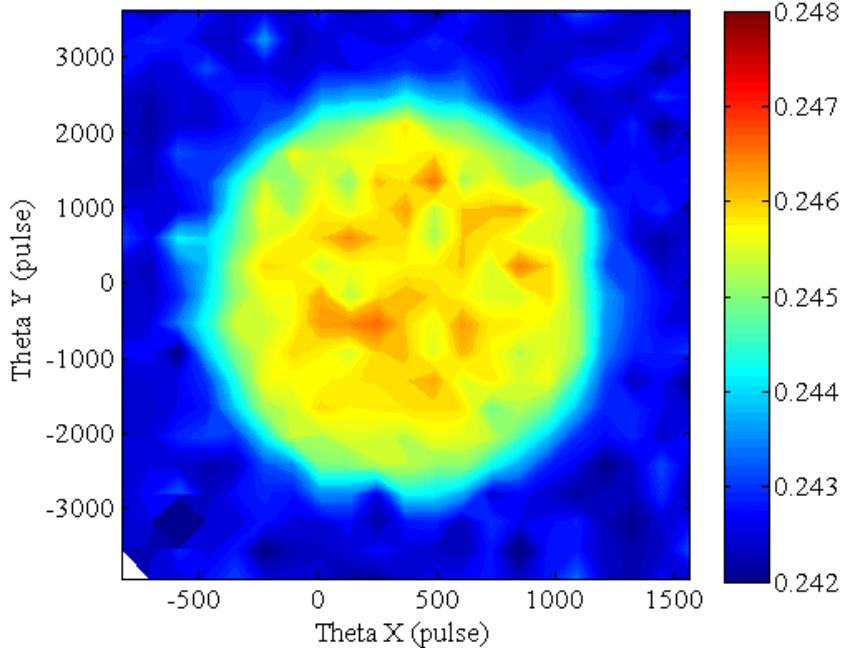


5.9315 keV

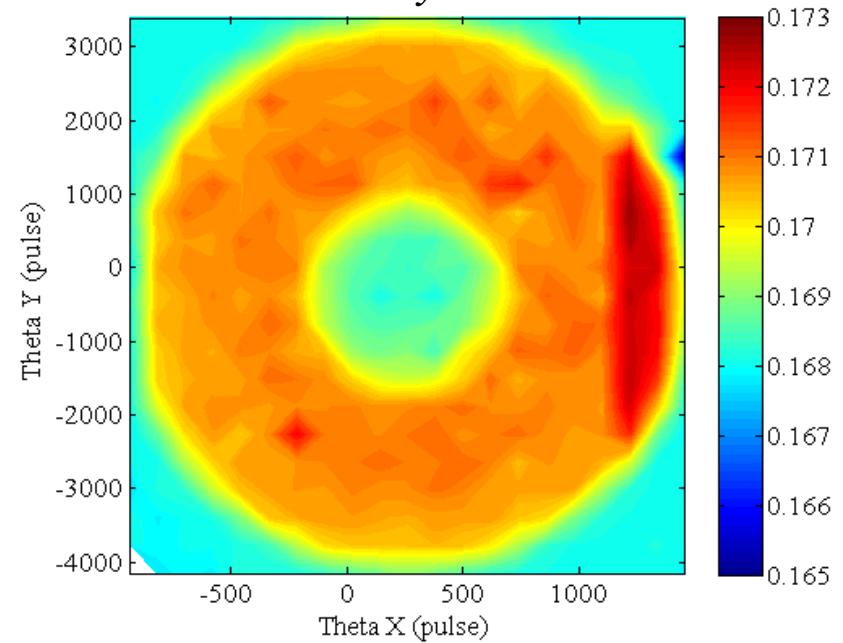
$\text{Si } (333) \ R \approx 0.11 \ (\sim 11\%)$

Scanning Pattern of ion-chamber output signal (I) by 2-axis (θ_x and θ_y) scanning

θ_x and θ_y : ± 1.5



θ_x and θ_y : ± 1.5



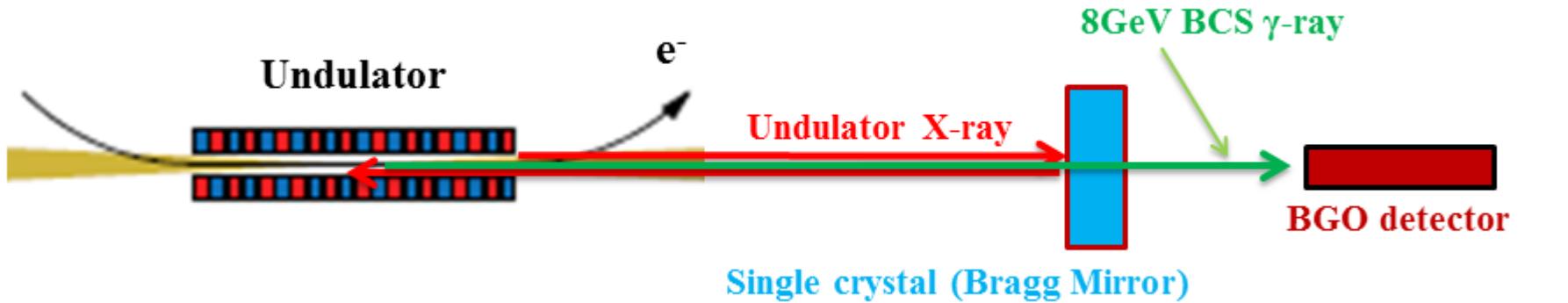
$\theta_x - \theta_y$ scan @ normal-incidence
of 9.132 keV

$\theta_x - \theta_y$ scan @ normal-incidence
of 9.133 keV

Photon energy of incident X-ray matched Bragg condition
at the normal-incidence (left) and unmatched (right).

Plan of Test Experiment for γ -ray Production

Schematic Drawing of γ -ray Production System



Multipole Wiggler

76mm \times 51 periods

$K_{\max} = 5.8$

Photon Energy = 5 ~ 30keV



Mirror Chamber

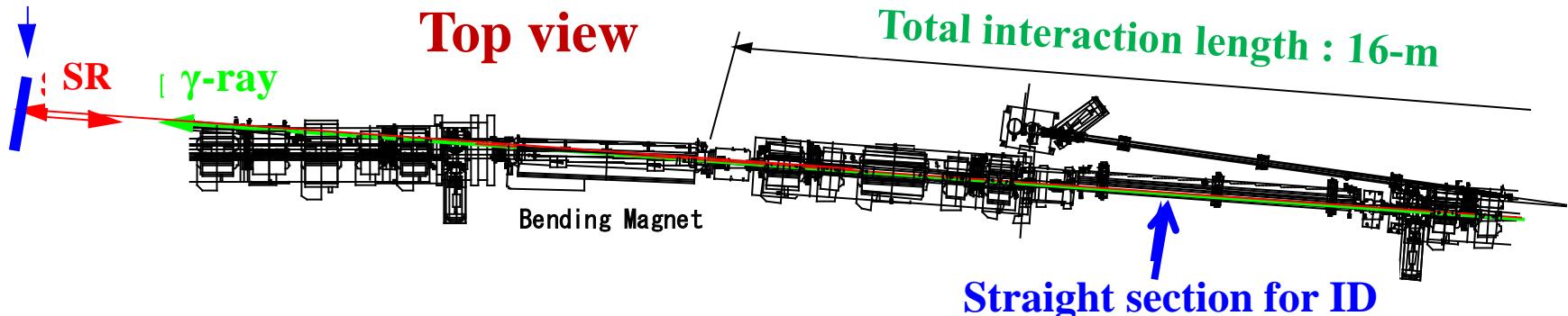
Mirror Cooling System

4-Axis Goniometer

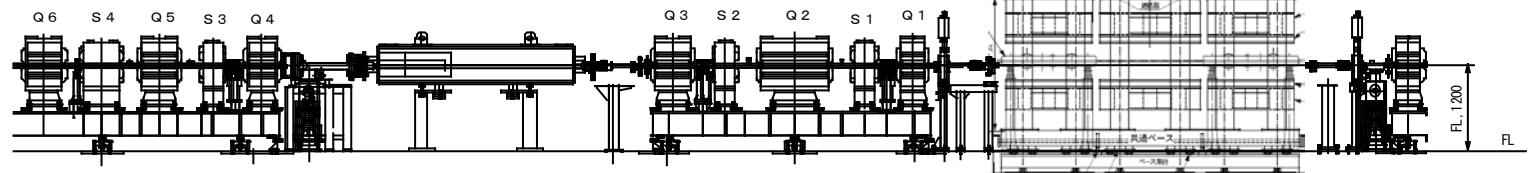


Plan of GeV Photons production at a beam diagnostics beamline, BL05SS

Single Crystal Mirror



Side View



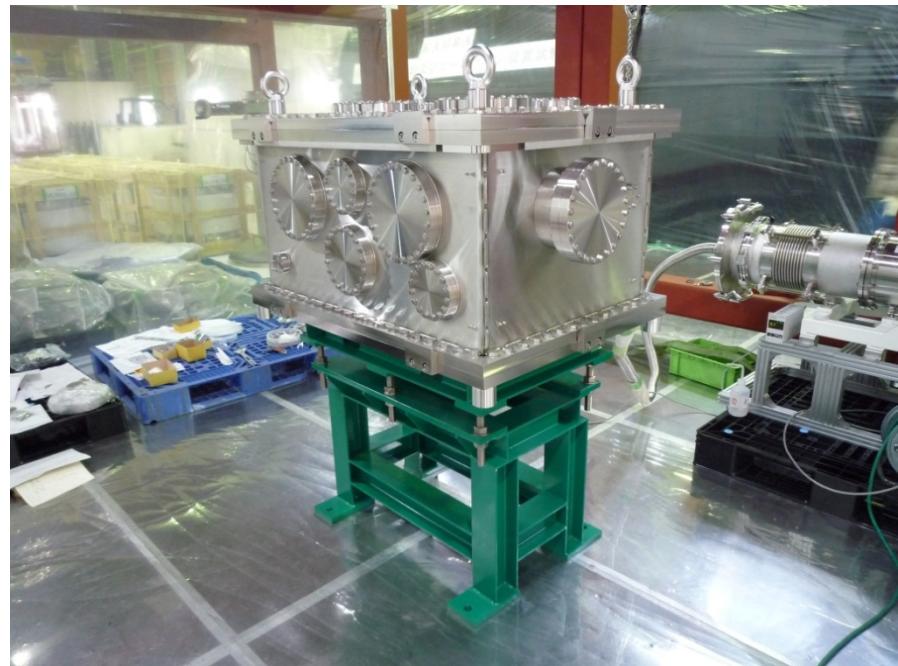
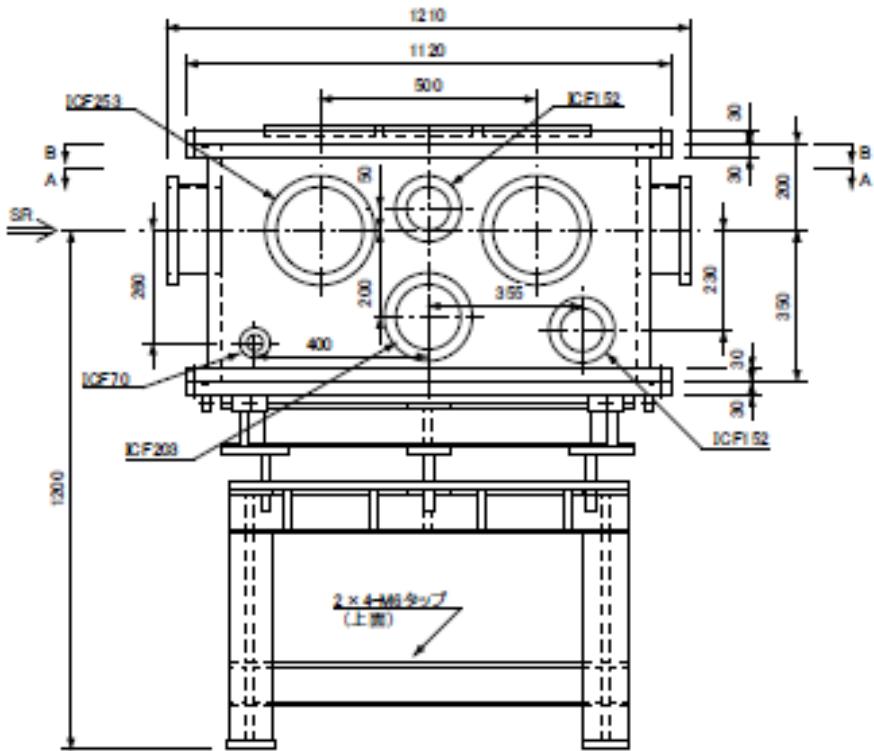
Multipole Wiggler

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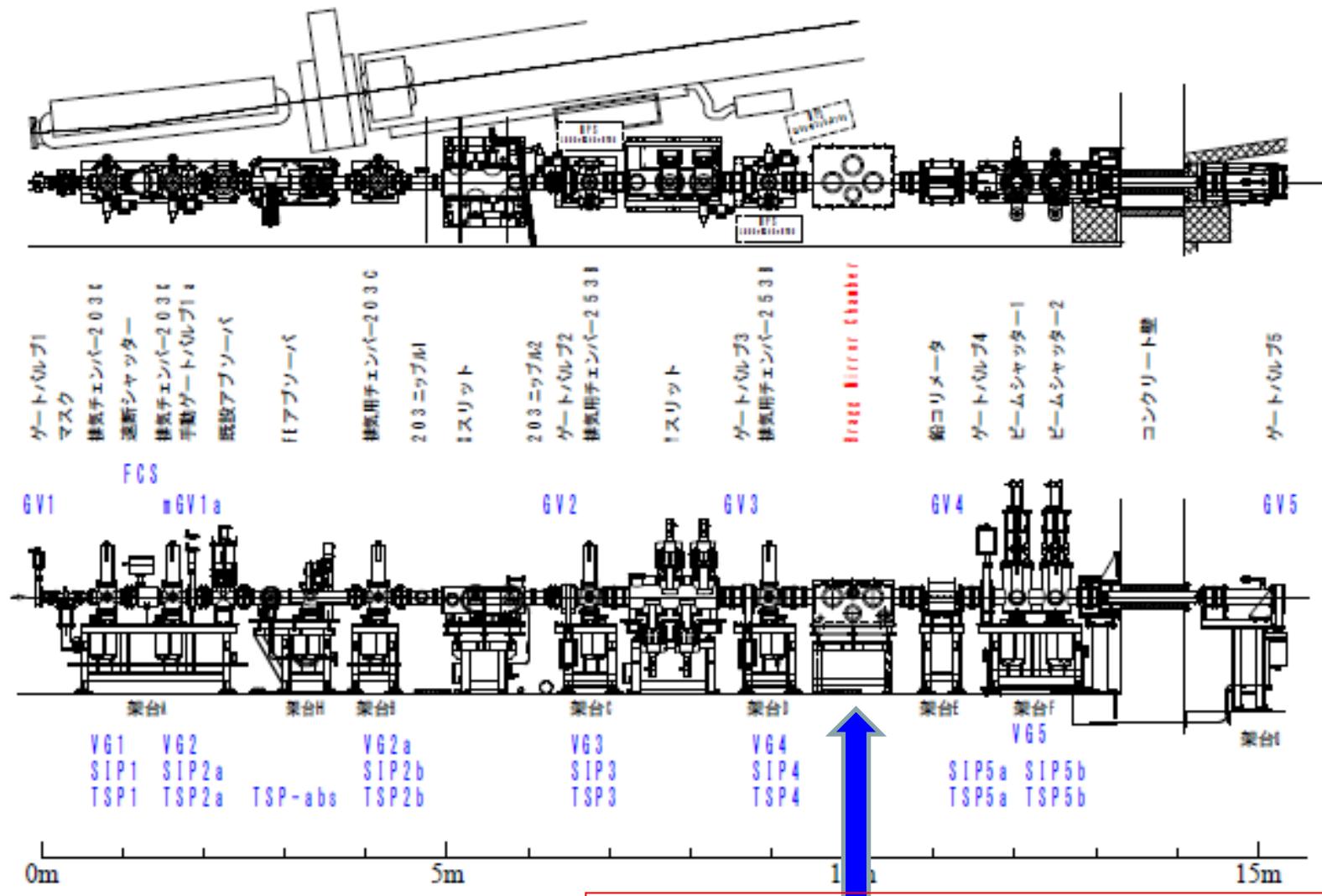
Mirror Chamber



Outer Dimension : 1120 mm × 820 mm × 610 mm

**Mirror mounting system with cooling device
4-Axis Goniometer
(Focusing System)**

Front-end of BL05SS at SPring-8



Mirror Chamber (29m from ID center)

Summary

- We proposed backward Compton scattering using undulator radiation to reflect back by Bragg mirror.
- Preliminary reflectivity measurement of silicon single crystal.
- Experimental setup of γ -ray production by BCS using a single crystal (diamond) is now under preparation.

Thank you for your attention